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Paper No. 6

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JAN 18 2001

OFFICE OF PETITIONS

A/C PATENTS

DECISION GRANTING STATUS  
UNDER 37 CFR 1.47(a)

In re Application of  
Meisburger, et al.  
Application No. 09/502,120  
Filed: February 10, 2000  
Title of Invention: INSPECTING OPTICAL  
MASKS WITH ELECTRON BEAM  
MICROSCOPY

This is a decision on the Petition under 37 CFR 1.47(a), filed October 2, 2000, to proceed with the above-identified patent application where a joint inventor refuses to join the application.

The Petition is **granted**.

The above-identified application and papers have been reviewed and found in compliance with 37 CFR 1.47(a). This application is hereby accorded Rule 47(a) status.

Petitioner has shown that the non-signing inventor refuses to sign the declaration after having been presented with the above-identified application and declaration. Specifically, Petitioner established that the non-signing inventor, Mr. Dan Meisburger, refuses to sign the declaration after having been presented with the application, including the specification, claims, drawings, declaration, and assignment documents in the above-identified application.

As provided in Rule 1.47(a), this Office will forward notice of this application's filing to the non-signing inventor at the address given in the Petition. Notice of the filing of this application will also be published in the Official Gazette.

The application file is being forwarded to Technology Center 2800 for further processing.

Telephone inquiries regarding this communication should be directed to Petitions Attorney Derek L. Woods at (703) 305-0014.

Beverly M. Flanagan  
Supervisory Petitions Examiner  
Office of Petitions  
Office of the Deputy Commissioner  
for Patent Examination Policy



Dan Meisburger  
1507 Montalban Drive  
San Jose, CA 95120-4830

LETTER

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In re Application of  
Meisburger, et al.  
Application No. 09/502,120  
Filed: February 10, 2000  
Title of Invention: INSPECTING OPTICAL  
MASKS WITH ELECTRON BEAM  
MICROSCOPY

Dear Mr. Meisburger:

You are named as a joint inventor in the above-identified United States patent application filed under the provisions of 35 U.S.C. 116 (United States Code) and 37 CFR 1.47(a), Rules of Practice in Patent Cases. Should a patent be granted on the application you will be designated therein as a joint inventor.

As a named inventor you are entitled to inspect any paper in the file wrapper of the application, order copies of all or any part thereof (at a prepaid cost per 37 CFR 1.19) or make your position of record in the application. Alternatively, you may arrange to do any of the preceding through a registered patent attorney or agent presenting written authorization from you. If you care to join the application, counsel of record (see below) would presumably assist you. Joining in the application would entail the filing of an appropriate oath or declaration by you pursuant to 37 CFR 1.63.

Telephone inquiries regarding this communication should be directed to Petitions Attorney Derek L. Woods at (703) 305-0014. Requests for information regarding your application should be directed to the File Information Unit at (703) 308-2733. Information regarding how to pay for and order a copy of the application, or a specific paper in the application, should be directed to Certification Division at (703) 308-9726 or 1-800-972-6382 (outside the Washington D.C. area).

Beverly M. Flanagan  
Supervisory Petitions Examiner  
Office of Petitions  
Office of the Deputy Commissioner  
for Patent Examination Policy

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